

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No. 09/546,174	Confirmation No.: 4793
In re Application of: Chih-Chien Liu, et al.	Art Unit: 1711
Filed: April 11, 2000	Examiner: Sergeant, Rabon A.
For: HIGH DENSITY PLASMA CHEMICAL VAPOR DEPOSITION PROCESS	Customer No.: 26021

RESPONSE TO OFFICE ACTION DATED June 20, 2007

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This response is filed with a petition for three month extension of the period for response and is in response to the Office Action mailed June 20, 2007. Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this paper.

Remarks begin on page 9 of this paper.